

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S58	318	134/133-135,137,140,145.ccls. and (wafer or semiconductor or substrate or workpiece)	US-PGPUB; USPAT	OR	ON	2007/04/24 18:44
S59	21	134/133-135,137,140,145.ccls. and (wafer or semiconductor or substrate or workpiece) same (nozzle or plate) near10 (connect\$3 or attach\$3) near10 (hold\$3 or support\$3)	US-PGPUB; USPAT	OR	ON	2007/04/25 13:18
L3	1	134/133-135,137,140,145,902. ccls. and (wafer or semiconductor or substrate or workpiece) same (nozzle near10 plate) near10 (connect\$3 or attach\$3) near10 (hold\$3 or support\$3) and (load\$3 same unload\$3 same process\$3)	US-PGPUB; USPAT	OR	ON	2007/04/25 13:19
L4	487	(wafer or semiconductor or substrate or workpiece) same (nozzle or plate) near10 (connect\$3 or attach\$3) near10 (hold\$3 or support\$3) and (load\$3 same unload\$3 same process\$3)	US-PGPUB; USPAT	OR	ON	2007/04/25 13:47
L6	60	5 not 2	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT	OR	ON	2007/04/25 13:49
L8	0	(wafer or semiconductor or substrate or workpiece) near15 (nozzle with plate) near10 (connect\$3 or attach\$3) near10 (hold\$3 or support\$3) and (load\$3 near10 unload\$3 near10 process\$3) near10 (chamber\$3)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT	OR	ON	2007/04/25 13:53
L7	0	(wafer or semiconductor or substrate or workpiece) near15 (nozzle near6 plate) near10 (connect\$3 or attach\$3) near10 (hold\$3 or support\$3) and (load\$3 near10 unload\$3 near10 process\$3) near10 (chamber\$3)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT	OR	ON	2007/04/25 13:53

EAST Search History

L5	70	(wafer or semiconductor or substrate or workpiece) near15 (nozzle or plate) near10 (connect\$3 or attach\$3) near10 (hold\$3 or support\$3) and (load\$3 near10 unload\$3 near10 process\$3) near10 (chamber\$3)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT	OR	ON	2007/04/25 13:53
L20	1	"5729856".pn.	US-PGPUB; USPAT	OR	ON	2007/04/25 14:41
L19	4	"5929856"	US-PGPUB; USPAT	OR	ON	2007/04/25 14:41
L2	41	134/133-135,137,140,145,902.ccls. and (wafer or semiconductor or substrate or workpiece) same (nozzle or plate) near10 (connect\$3 or attach\$3) near10 (hold\$3 or support\$3) and (load\$3 same unload\$3 same process\$3)	US-PGPUB; USPAT	OR	ON	2007/04/25 15:16
L21	0	134/151.ccls. and (wafer or semiconductor or substrate or workpiece) same (nozzle or plate) near10 (connect\$3 or attach\$3) near10 (hold\$3 or support\$3) and (load\$3 same unload\$3 same process\$3)	US-PGPUB; USPAT	OR	ON	2007/04/25 15:21
L22	7	134/151,95.2.ccls. and (wafer or semiconductor or substrate or workpiece) same (nozzle or plate) near10 (connect\$3 or attach\$3) near10 (hold\$3 or support\$3) and (load\$3 same unload\$3 same process\$3)	US-PGPUB; USPAT	OR	ON	2007/04/25 15:23
L23	0	(wafer chamber load unload sidewall holders plate nozzles connected move).clm.	US-PGPUB; USPAT	AND	ON	2007/04/25 15:24